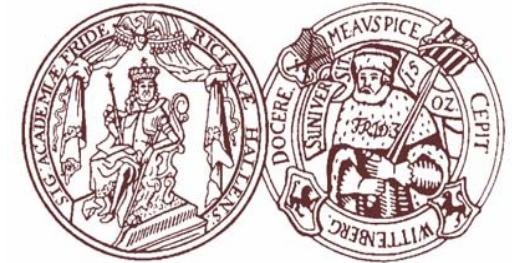


Positron Beam Application to Materials Science and Intense Accelerator or Reactor based Positron Beam Facilities in Germany

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Martin-Luther-Universität Halle-Wittenberg, Germany

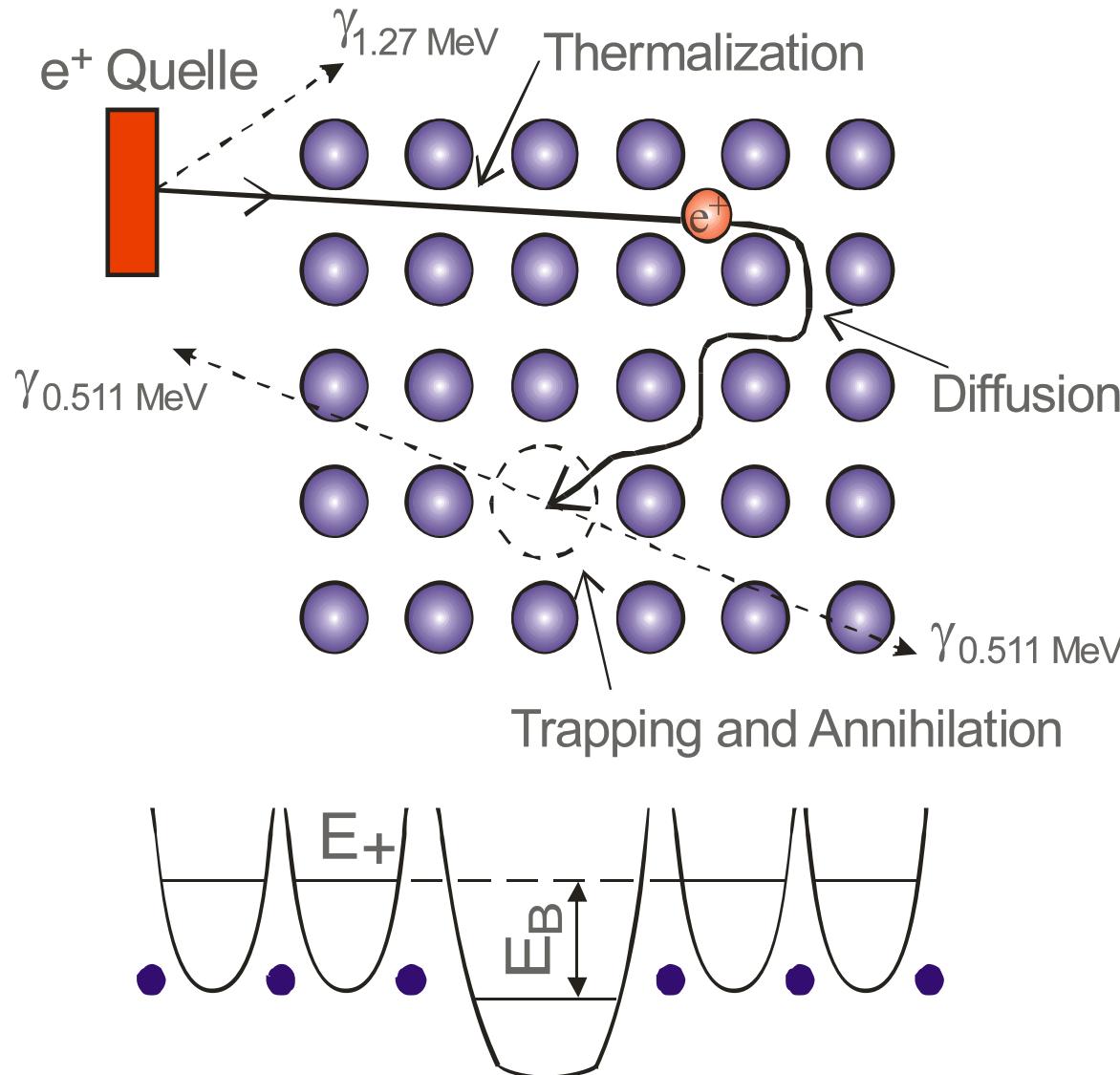
Martin-Luther-Universität



Halle-Wittenberg

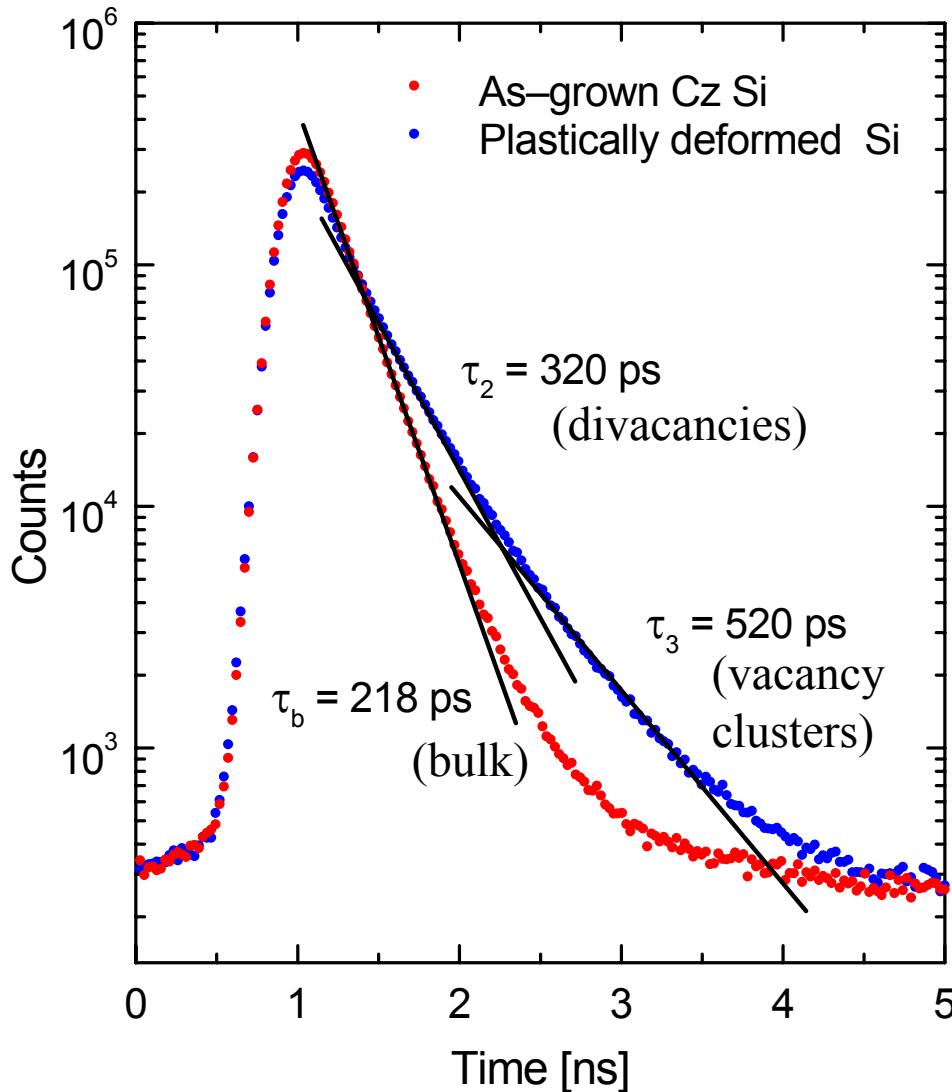
- Introduction: Positrons detect lattice defects
- Examples:
 - new getter centers in Si after high-energy self-implantation ($R_p/2$ effect)
 - study of defects in GaAs
- Large Positron Facility Projects in Germany
- Conclusions

The positron lifetime spectroscopy



- positron wave-function can be localized in the attractive potential of a defect
- annihilation parameters change in the localized state
- e.g. positron lifetime increases in a vacancy
- lifetime is measured as time difference between 1.27 and 0.51 MeV quanta
- defect identification and quantification possible

Positron lifetime spectroscopy



- positron lifetime spectra consist of exponential decay components
 - positron trapping in open-volume defects leads to long-lived components
 - longer lifetime due to lower electron density
 - analysis by non-linear fitting: lifetimes τ_i and intensities I_i

- positron lifetime spectrum:
$$N(t) = \sum_{i=1}^{k+1} \frac{I_i}{\tau_i} \exp\left(-\frac{t}{\tau_i}\right)$$

trapping coefficient

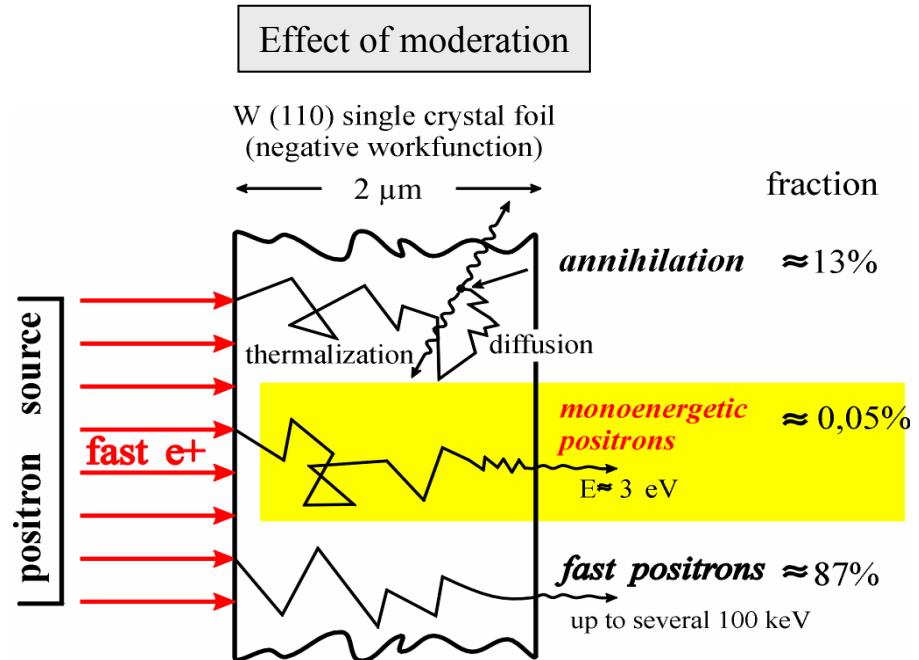
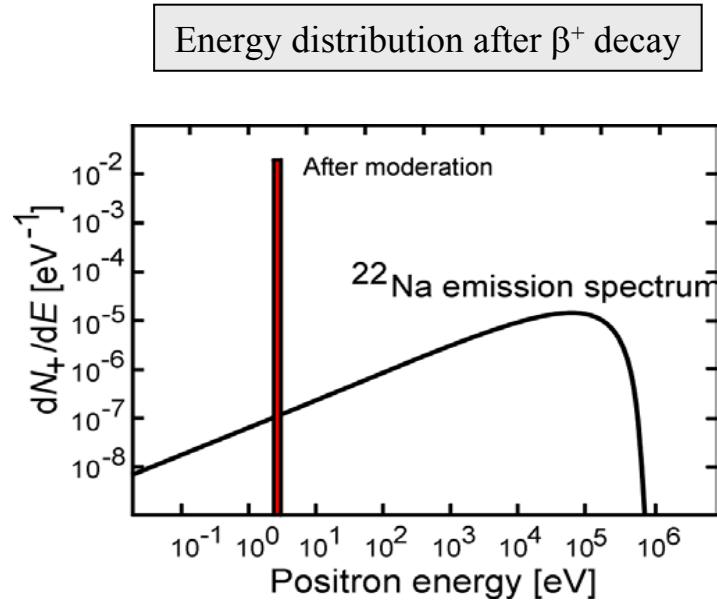
$$K_d = \mu C_d = \frac{I_2}{I_1} \left(\frac{1}{\tau_b} - \frac{1}{\tau_d} \right)$$

trapping rate

defect concentration

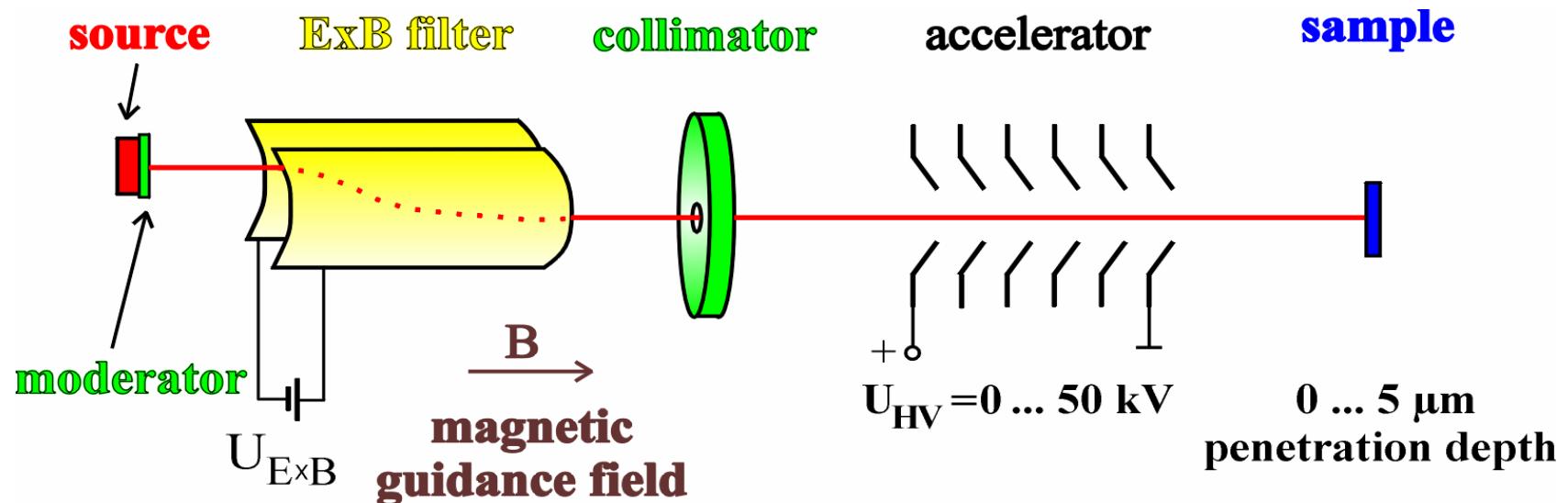
Monoenergetic positron beam by moderation

- positron annihilation was very successful in defect identification in last decades
- semiconductor technology: thin layers (epitaxy, ion implantation)
- broad energy distribution due to β^+ decay
- some surfaces: negative workfunction \Rightarrow moderation (but rather inefficient)



Conventional positron beam technique

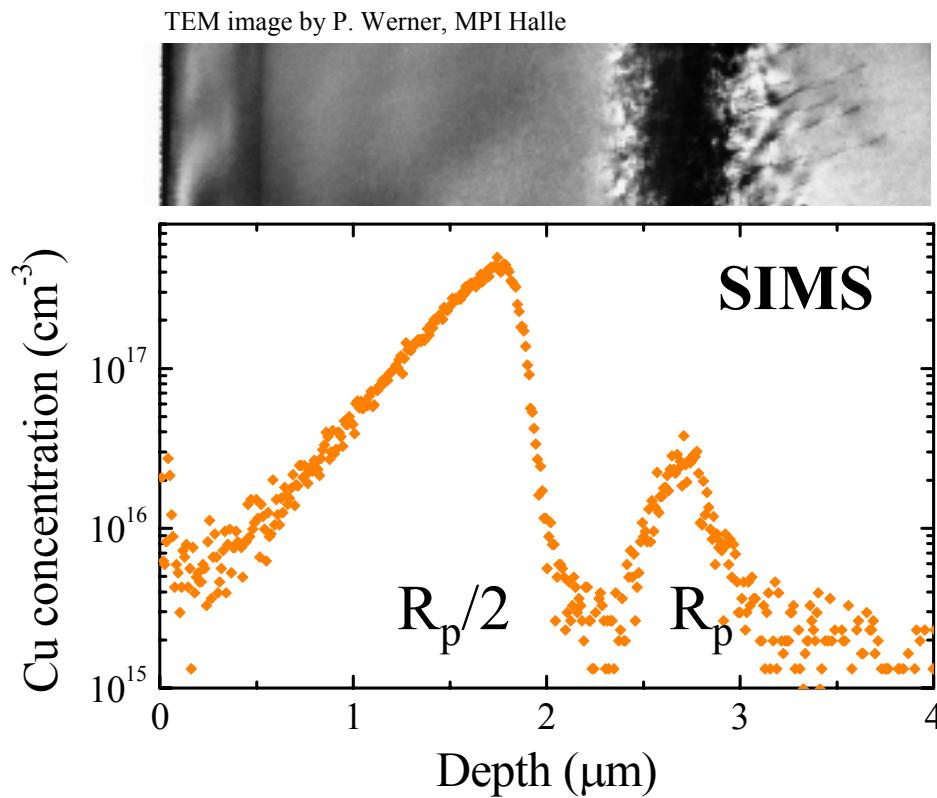
- positron beam can be formed using mono-energetic positrons
- often: magnetically guided for simplicity



- defect studies by Doppler-broadening spectroscopy
- characterization of defects only by line-shape parameters or positron diffusion length
- for positron lifetime spectroscopy: beam can be bunched

Defects in high-energy self-implanted Si — The $R_p/2$ effect

- after high-energy (3.5 MeV) self-implantation of Si ($5 \times 10^{15} \text{ cm}^{-2}$) and RTA annealing (900°C , 30s): two new gettering zones appear at R_p and $R_p/2$ (R_p = projected range of Si^+)
- visible by SIMS profiling after intentional Cu contamination



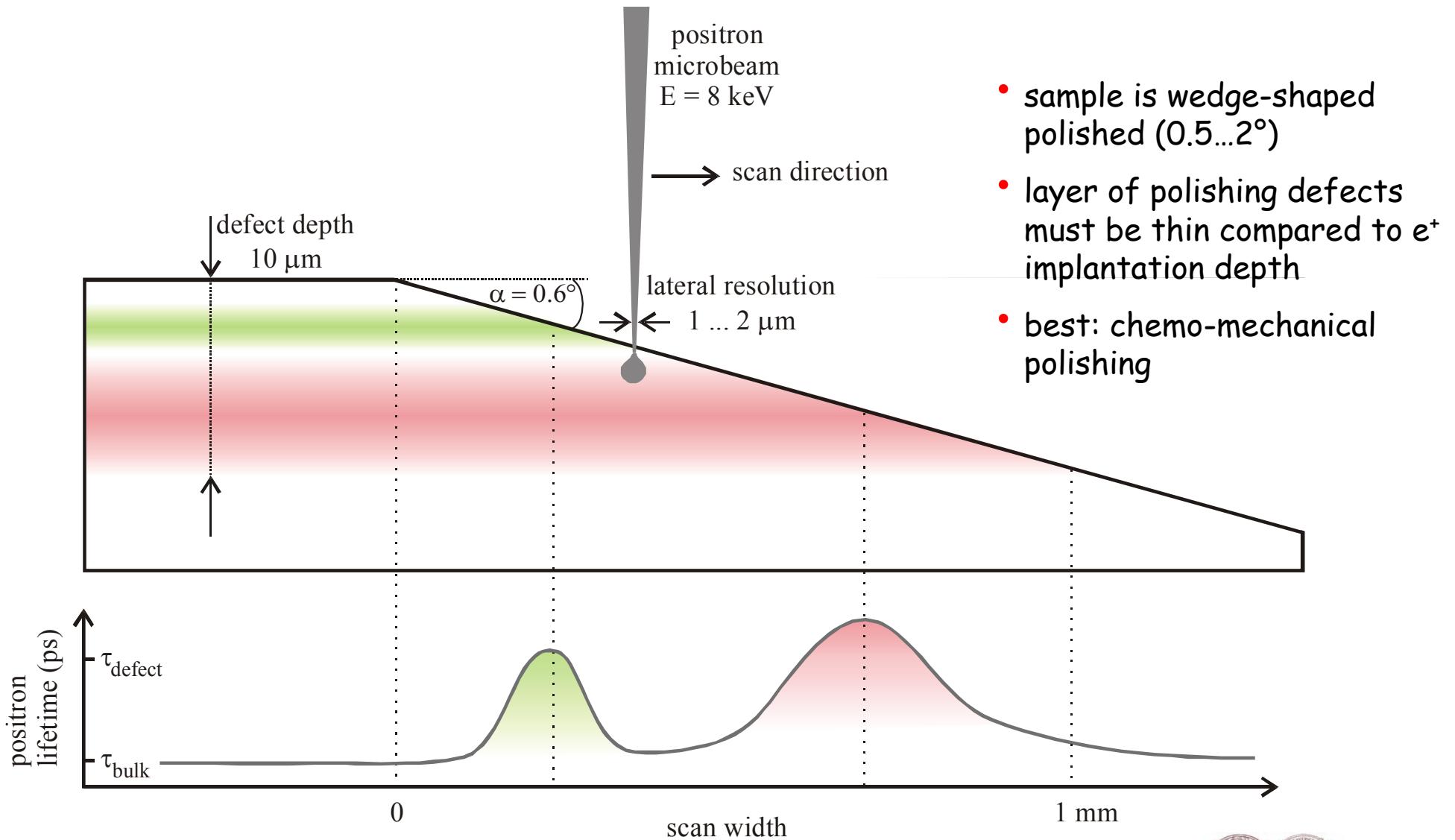
- at R_p : gettering by interstitial-type dislocation loops (formed by excess interstitials during RTA)
- no defects visible by TEM at $R_p/2$
- **What type are these defects?**

Interstitial type [3,4] Vacancy type [1,2]

Two red arrows point from the text labels "Interstitial type [3,4]" and "Vacancy type [1,2]" to the corresponding regions in the list above.

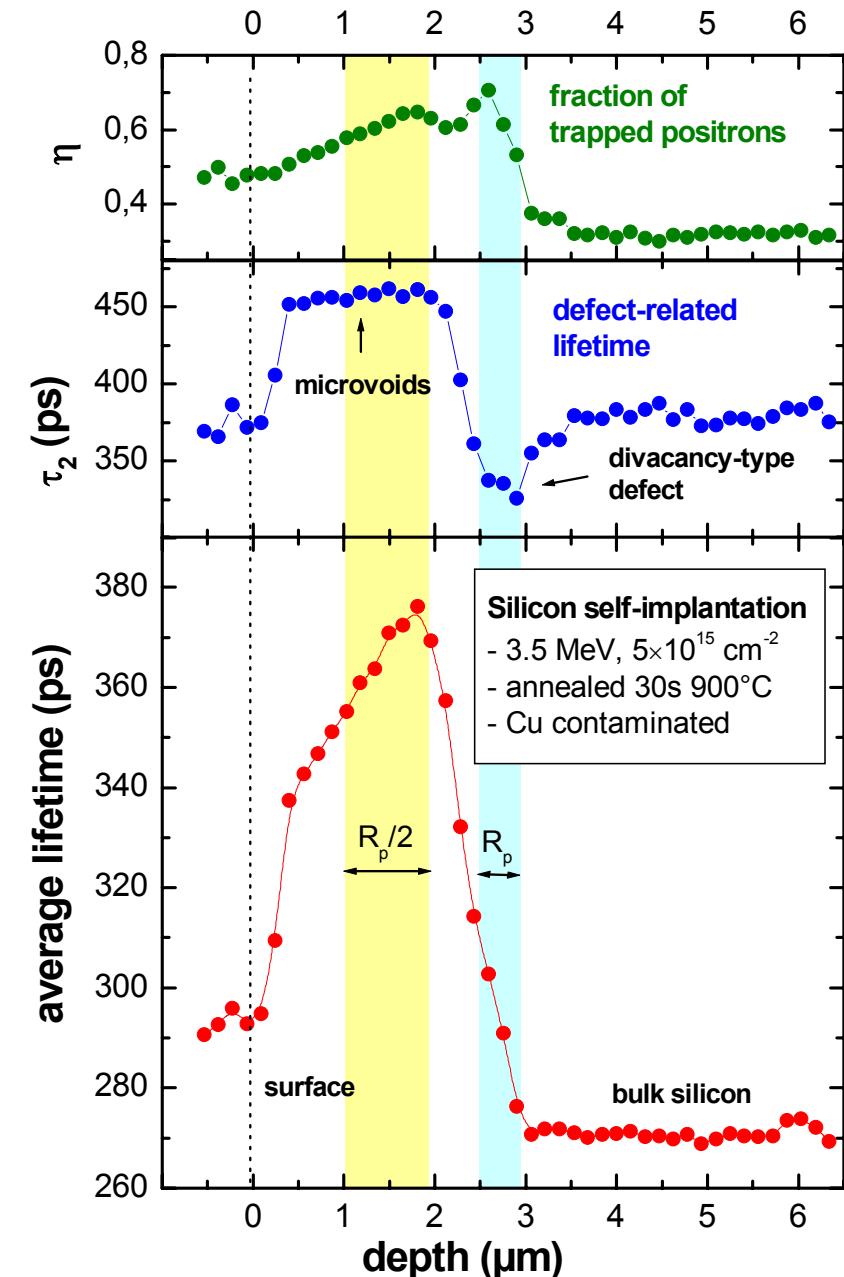
- [1] R. A. Brown, et al., J. Appl. Phys. **84** (1998) 2459
- [2] J. Xu, et al., Appl. Phys. Lett. **74** (1999) 997
- [3] R. Kögler, et al., Appl. Phys. Lett. **75** (1999) 1279
- [4] A. Peeva, et al., NIM B **161** (2000) 1090

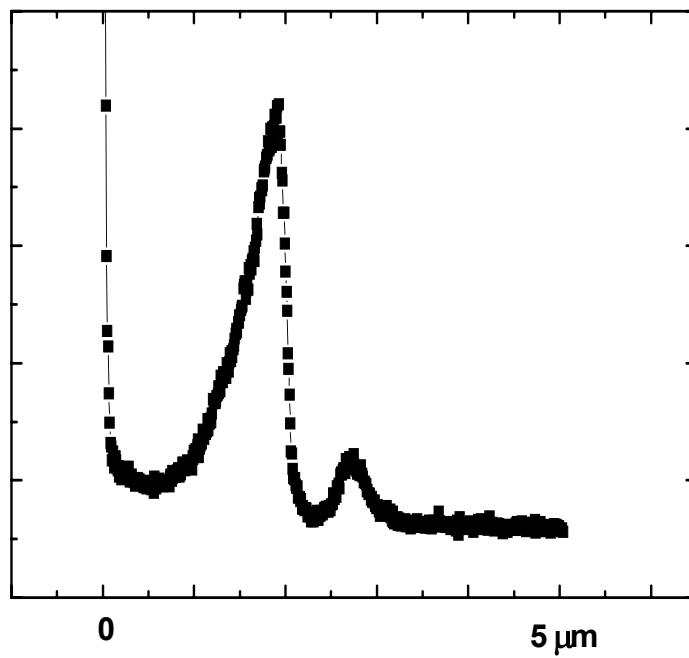
Enhanced depth resolution by using the Munich Scanning Positron Microscope



First defect depth profile using Positron Microscopy

- 45 lifetime spectra: scan along wedge
- separation of $11 \mu\text{m}$ between two measurements corresponds to depth difference of 155 nm ($\alpha = 0.81^\circ$)
- beam energy of $8 \text{ keV} \Rightarrow$ mean penetration depth is about 400 nm ; represents optimum depth resolution
- no further improvement possible due to positron diffusion: $L_+(Si @ 300K) \approx 230 \text{ nm}$
- both regions well visible:
 - vacancy clusters with increasing density down to $2 \mu\text{m}$ ($R_p/2$ region)
 - in R_p region: lifetime $\tau_2 = 330 \text{ ps}$; corresponds to open volume of a divacancy; must be stabilized or being part of interstitial-type dislocation loops

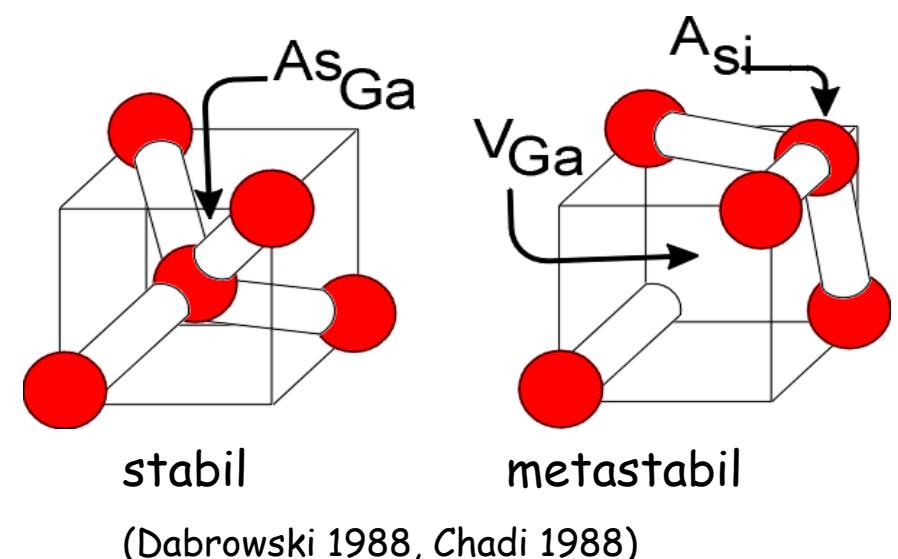
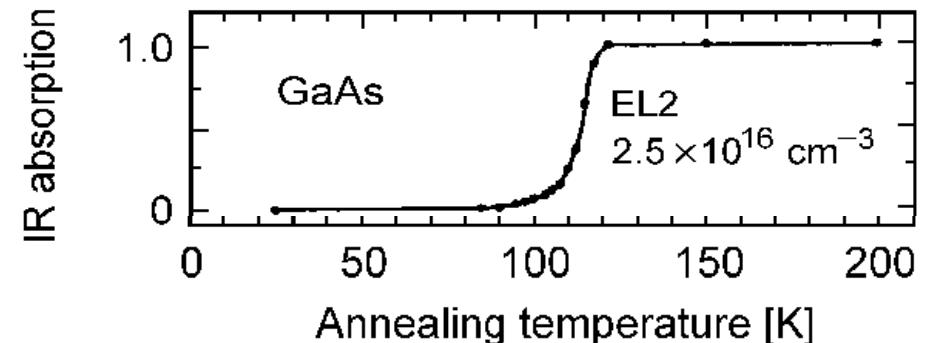




SIMS profile of Cu

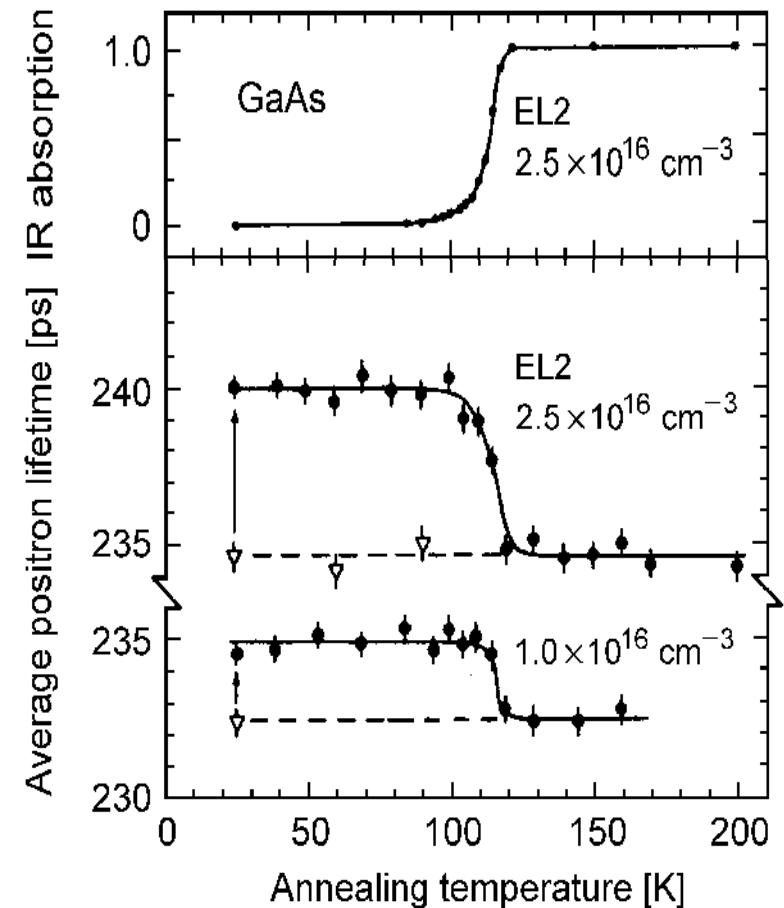
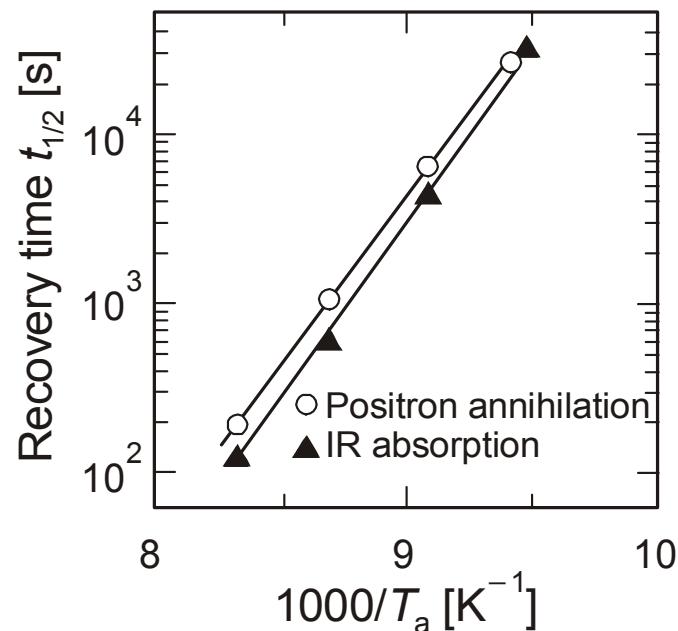
The Nature of the EL2-Defect in GaAs

- one of the most frequently studied crystal lattice defects at all
- responsible for semi-insulating properties of GaAs: large technological importance
- is deep donor, compensates shallow acceptors, e.g. C⁻ impurities
- defect shows metastable state after illumination at low temperatures
- IR-absorption of defect disappears during illumination at $T < 100$ K
- ground state recovers during annealing at about 110 K
- many structural models proposed
- Dabrowski, Scheffler and Chadi, Chang (1988): simple As_{Ga}-antisite defect responsible
- must show a metastable structural change



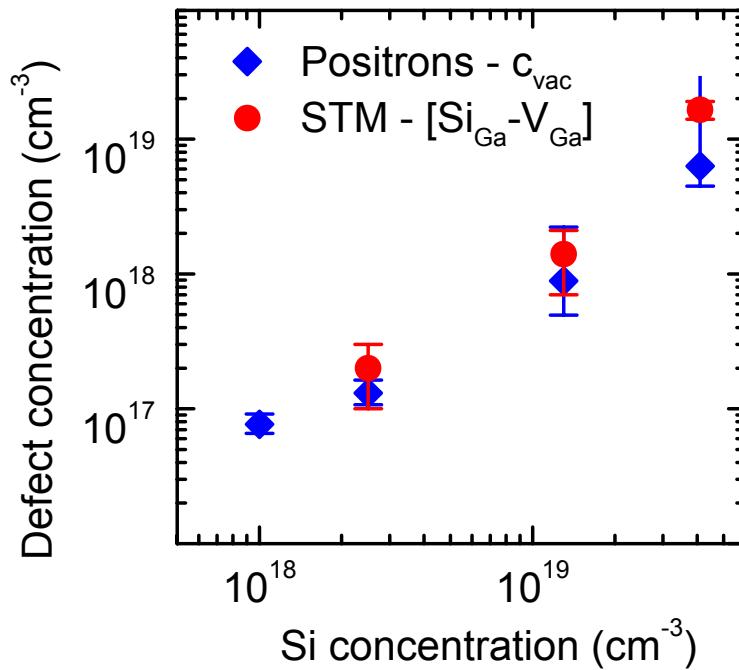
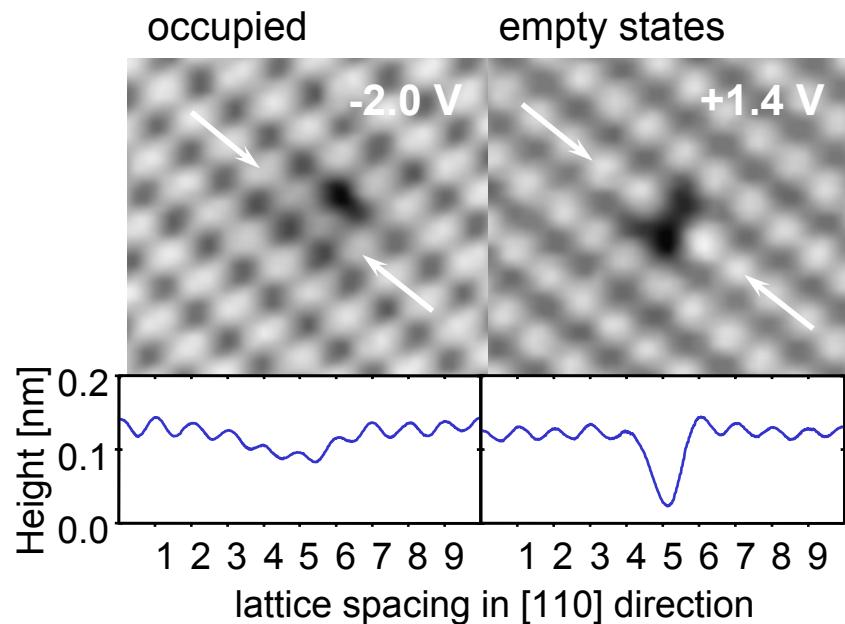
The Nature of the EL2-Defect in GaAs

- in metastable state at low temperature: Ga vacancy
- should disappear during annealing at about 110 K
- confirmed by positron lifetime measurements
- kinetics of recovery of ground state is identical for IR- und positron experiment: $E_A = (0.37 \pm 0.02) \text{ eV}$
- evidence of the vacancy in metastable state confirms the proposed structural model



Krause et al., Phys. Rev. Lett. **65** (1990) 3329

Identification von V_{Ga} - Si_{Ga} -Complexes in GaAs:Si



- Scanning tunneling microscopy at GaAs (110)-cleavages planes (by Ph. Ebert, Jülich)
- Defect complex identified as V_{Ga} - Si_{Ga}

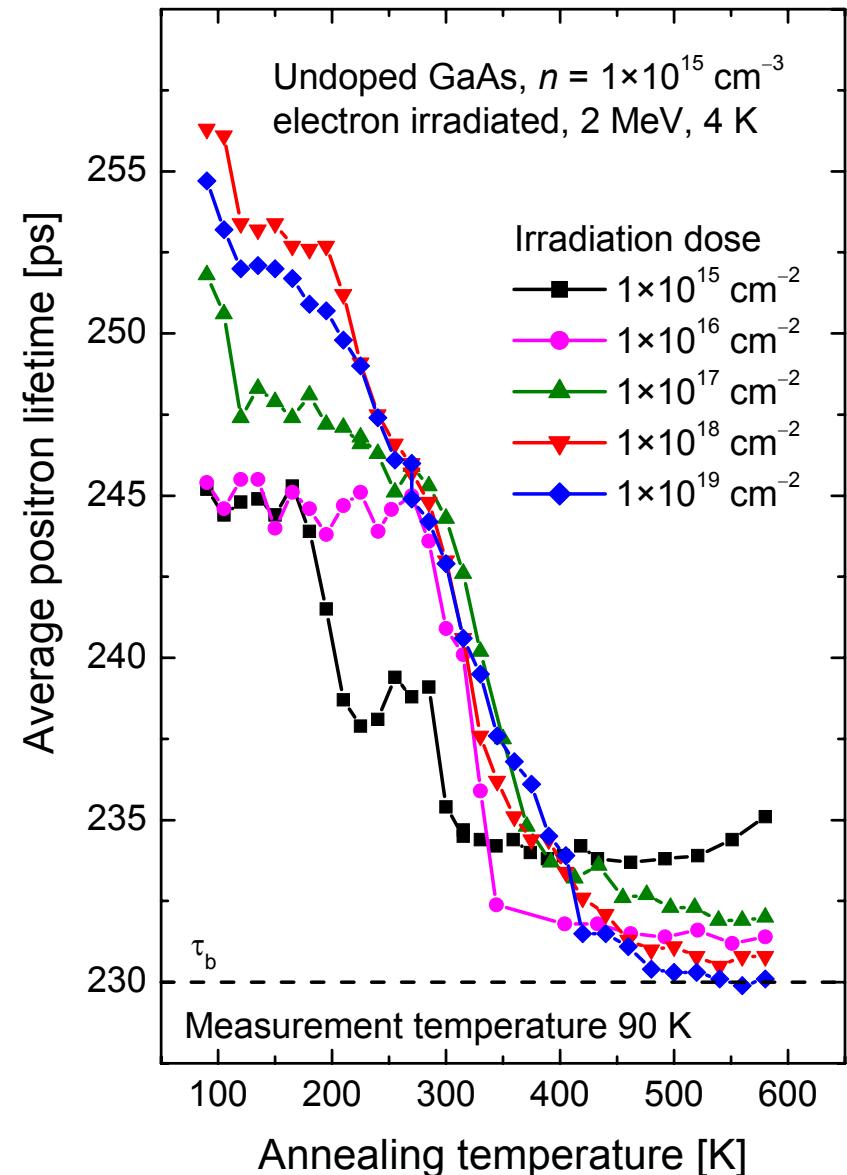
- Quantification → Agreement

Mono-vacancies in GaAs:Si are V_{Ga} - Si_{Ga} -complexes

Gebauer et al., Phys. Rev. Lett. **78**, 3334-3337 (1997)

electron-irradiated GaAs

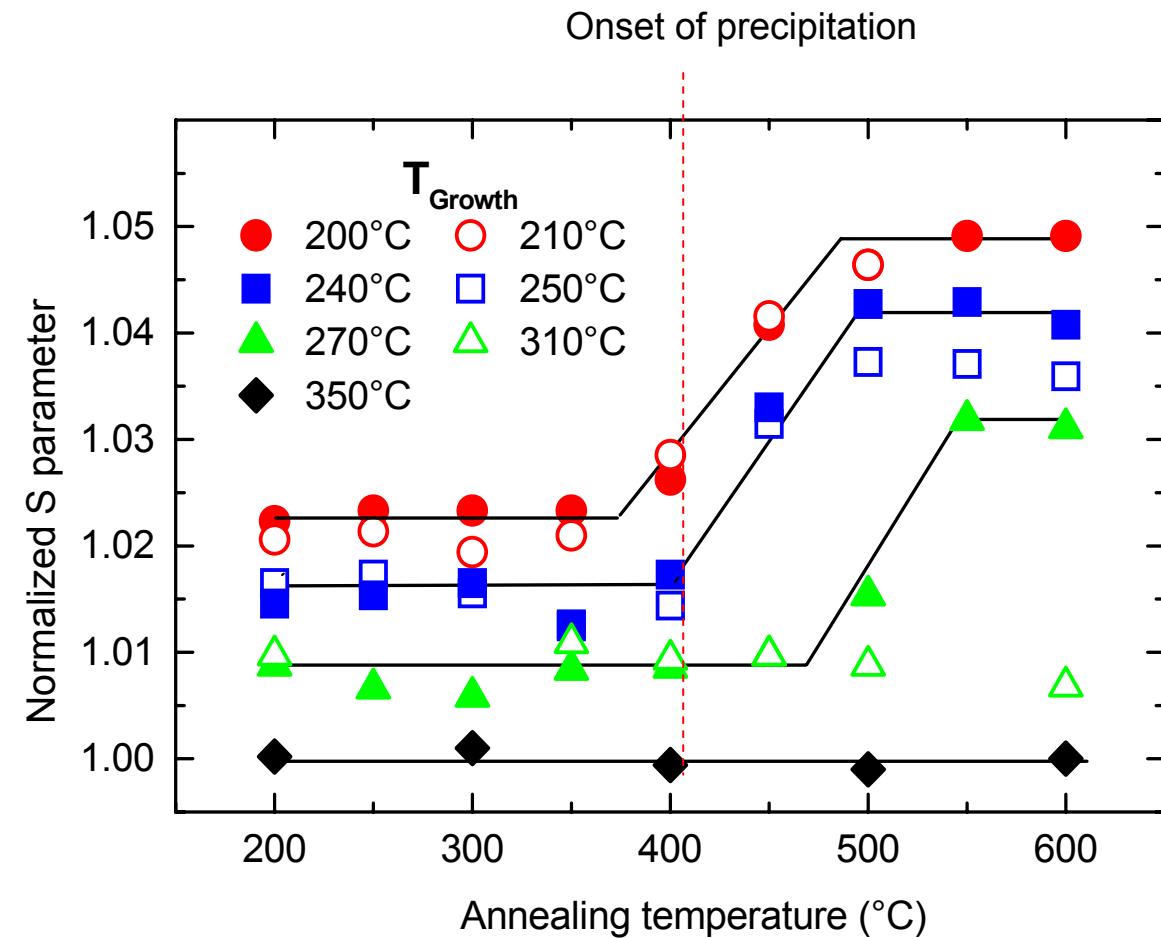
- electron irradiation generates vacancies in both sublattices
- very complex annealing behavior
- main annealing stage at 300 K
- similar annealing stage found for doped GaAs



A. Polity et al., Phys. Rev. B 55 (1997) 10467

Defects in epitaxially grown LT-GaAs-Layer

- MBE-Growth of GaAs can be performed at 200°C
- thickness of layer $\approx 1 \mu\text{m}$
- has unique properties, e.g. very short recombination time
- layer extremely rich of defects
- up to 1% As-excess is compensated by As_{Ga} und V_{Ga}
- Ga vacancies are seen by positrons
- during annealing: As-precipitation starts at 400°C
- positrons detect then small vacancy clusters
- clusters are probably bound to precipitates



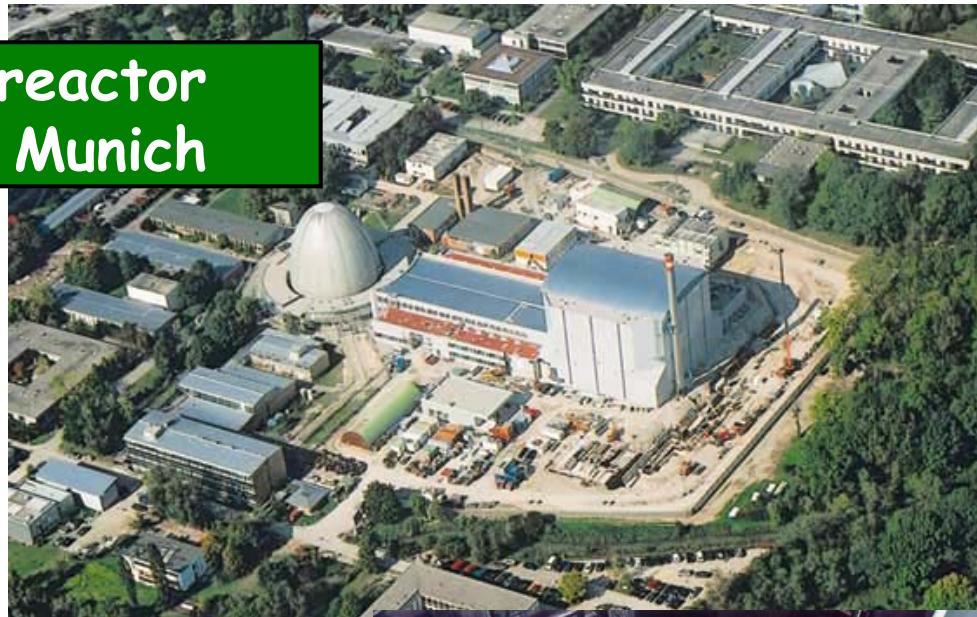
Gebauer et al., Appl. Phys. Lett. **71**, 638 (1997)

Large Positron Facility Projects in Germany

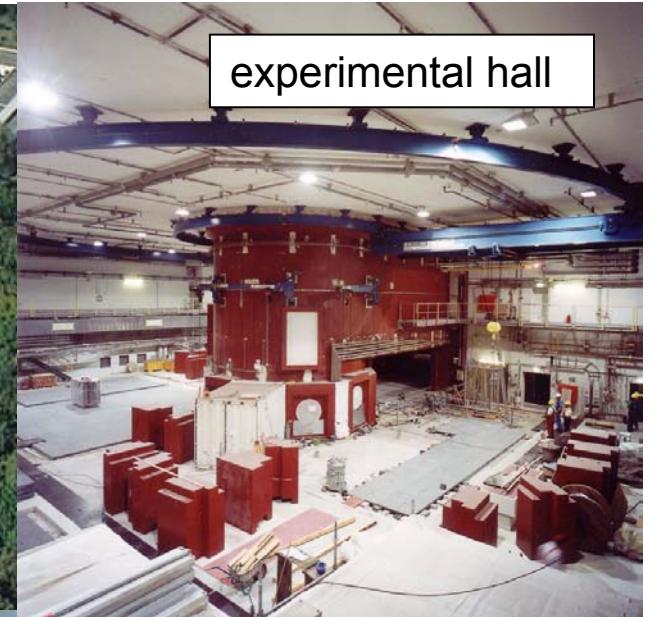
- **FRM-II** (Positron source at Research Reactor-II in Garching near Munich)
 - continuous positron beam for different experiments, mainly for:
- **Scanning Positron Microscope** at "Universität der Bundeswehr", Munich
 - system already working using ^{22}Na source
 - positron lifetime measurement; lateral resolution about $2 \mu\text{m}$
- **EPOS** - European Positron Source for applied Research (project at Research Center Rossendorf, near Dresden)
 - positron source for materials research at superconducting 40 MeV-FEL in Rossendorf
 - primary time structure suitable for positron lifetime spectroscopy



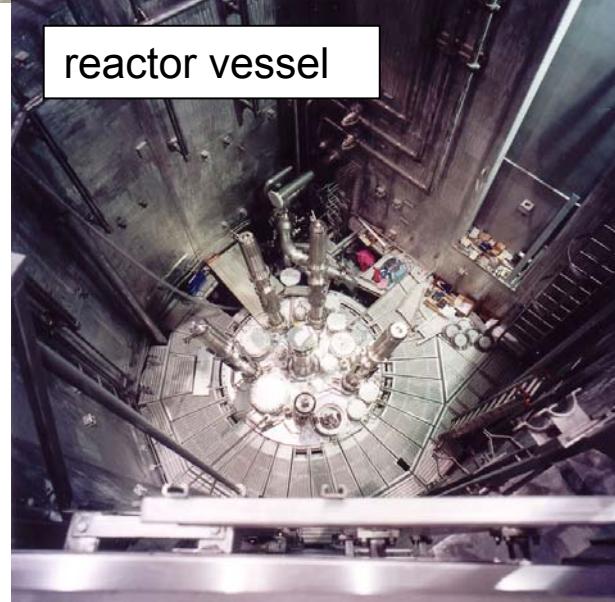
Research reactor FRM-II, Munich



experimental hall



reactor vessel

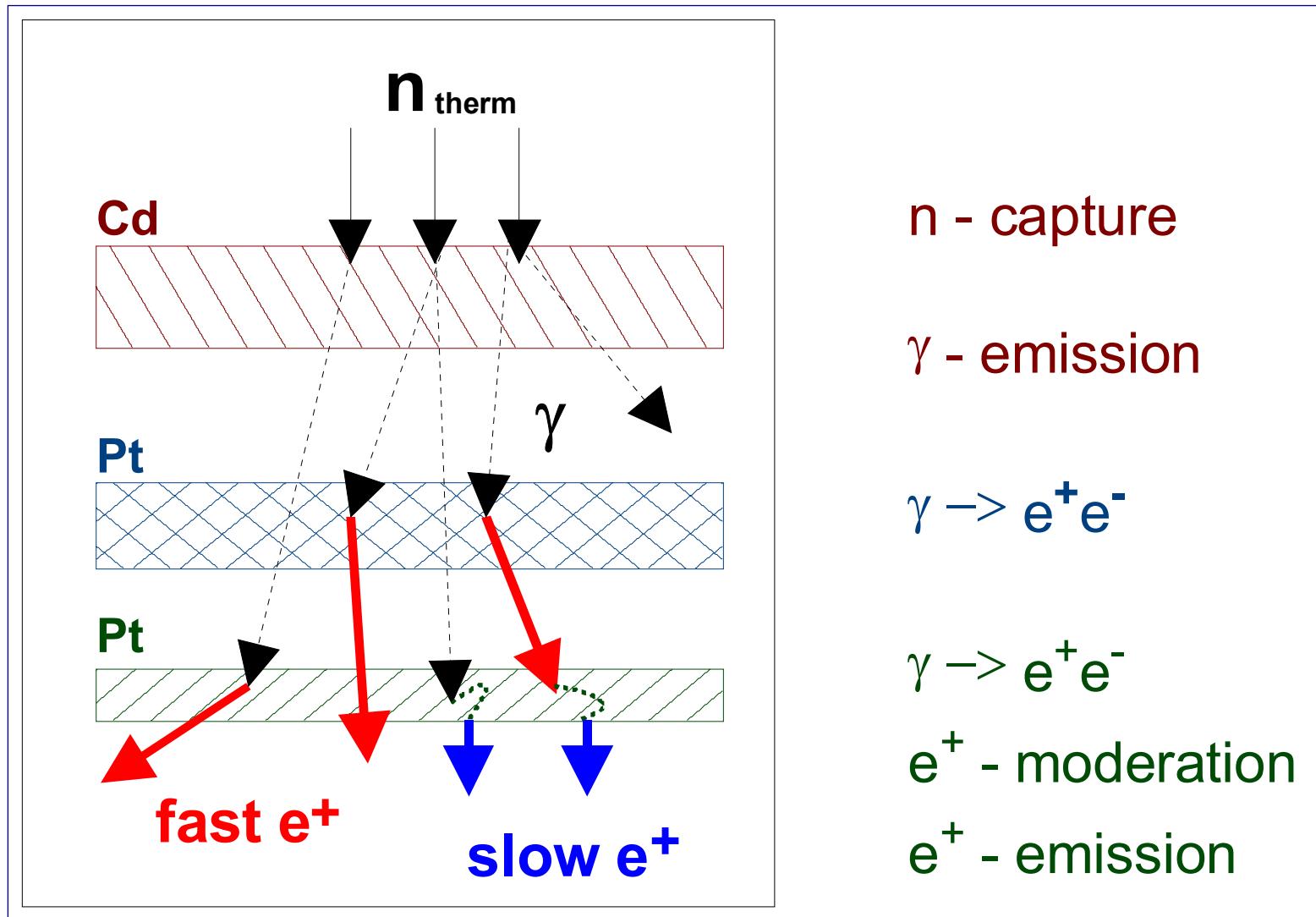


moderator tank



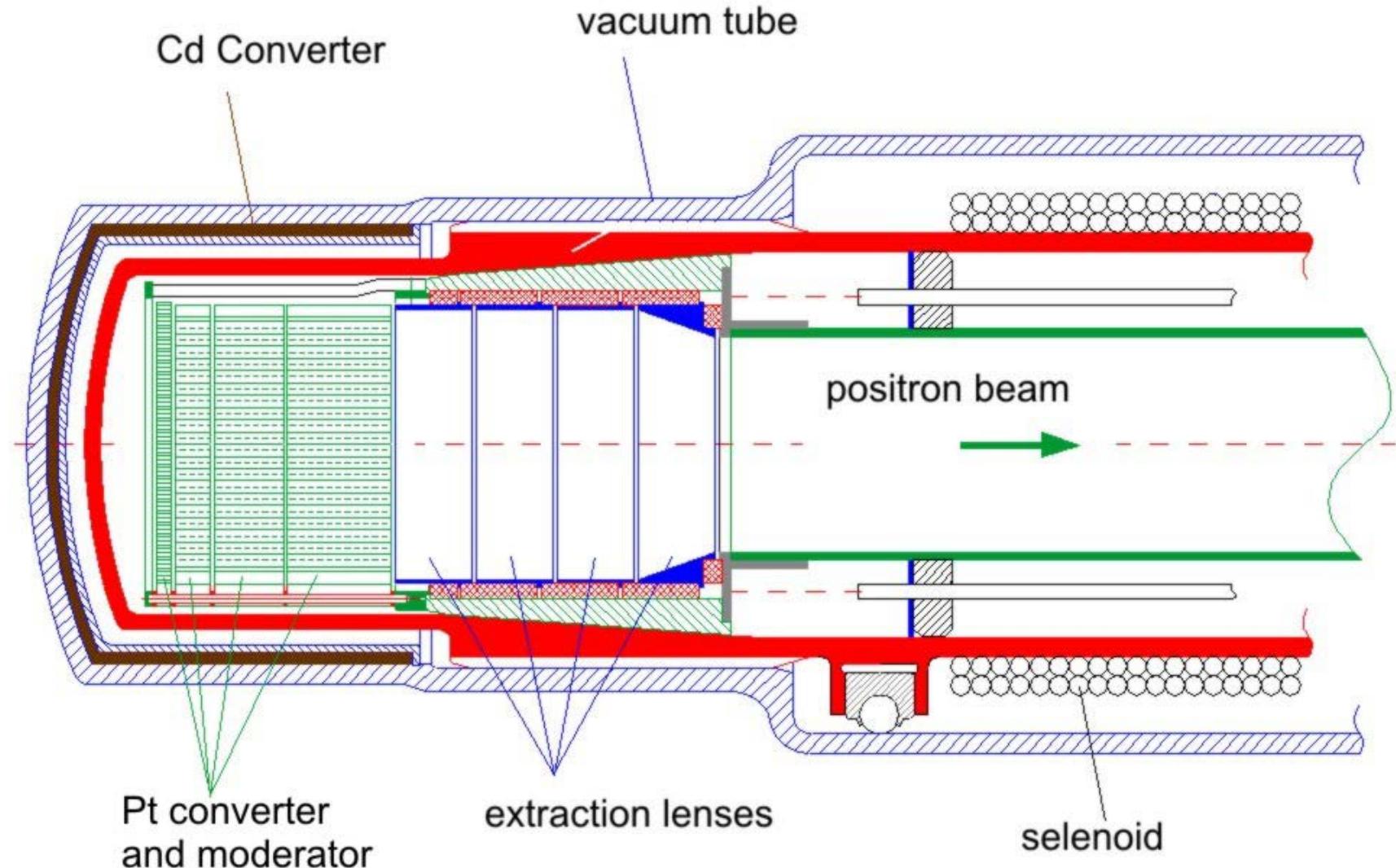
- positron generation by a nuclear reaction: $^{113}\text{Cd}(n,\gamma)^{114}\text{Cd}$
- three γ rays \rightarrow pair production
- continuous positron beam
- $\approx 10^{10}$ slow e^+ /s expected

Principle of the Positron Source at FRM-II



C. Hugenschmidt, 2002

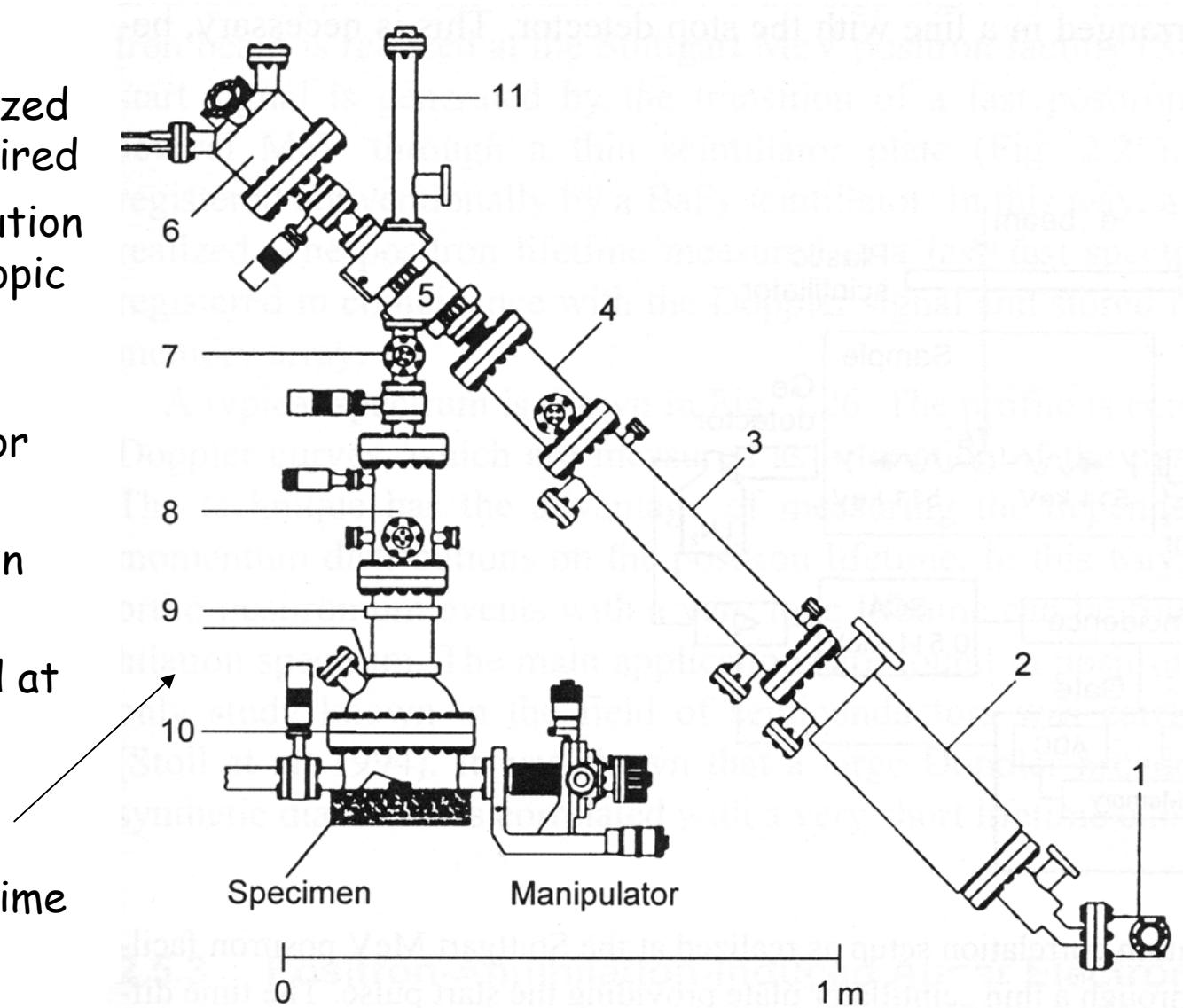
Design of the Positron Source at FRM-II



C. Hugenschmidt, 2002

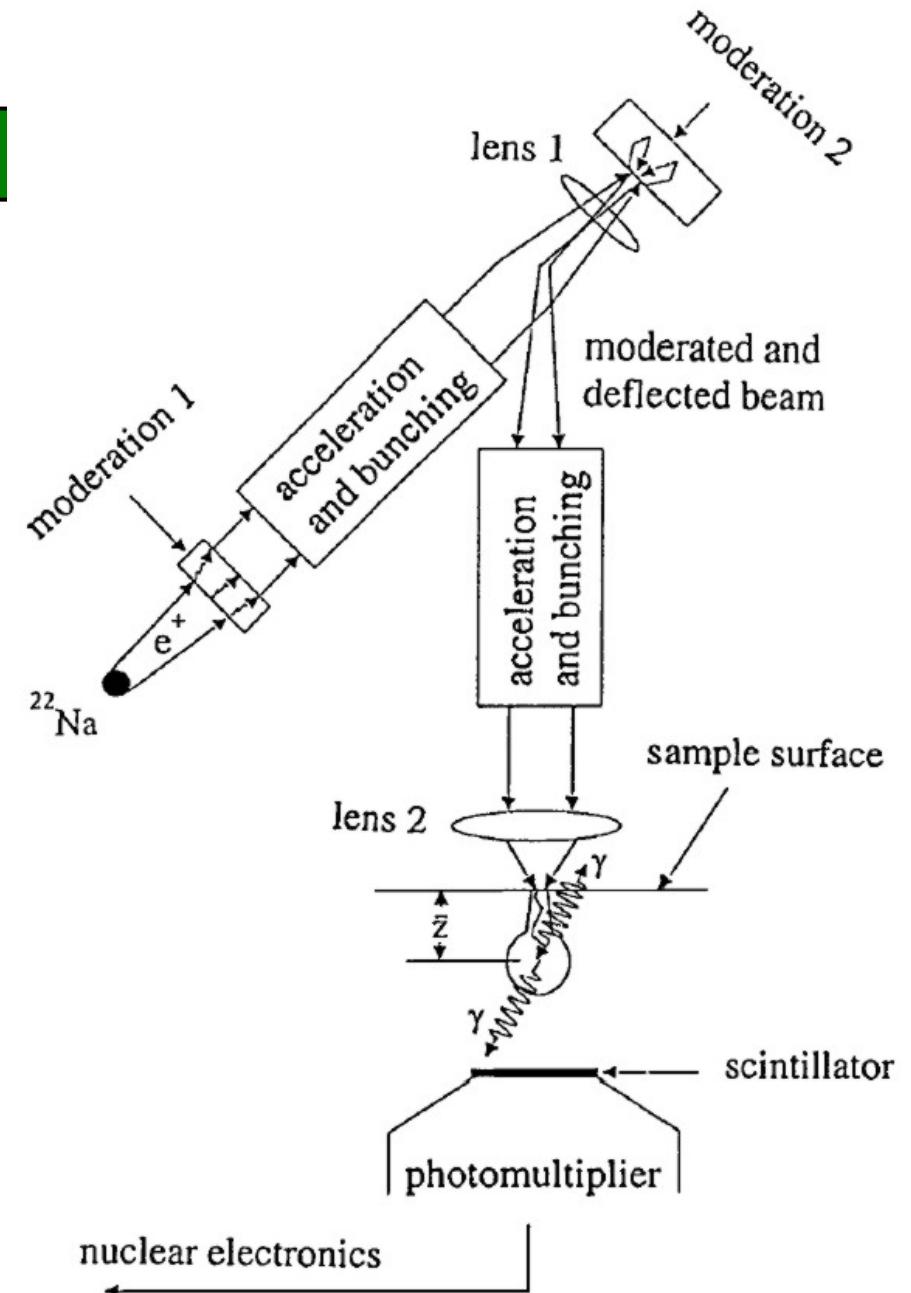
Scanning Positron Microscope in Munich

- Semiconductor devices nm-sized
⇒ Positron microprobes required
- images show directly distribution of positron traps, i.e. nanoscopic lattice defects
- However: positron diffusion length is fundamental limit for lateral resolution
- no sense to improve resolution much below 500 nm
- first instrument was realized at Univ. Bonn (20 μm ; Doppler spectroscopy)
- first realization of scanning positron microscope for lifetime spectroscopy: in Munich

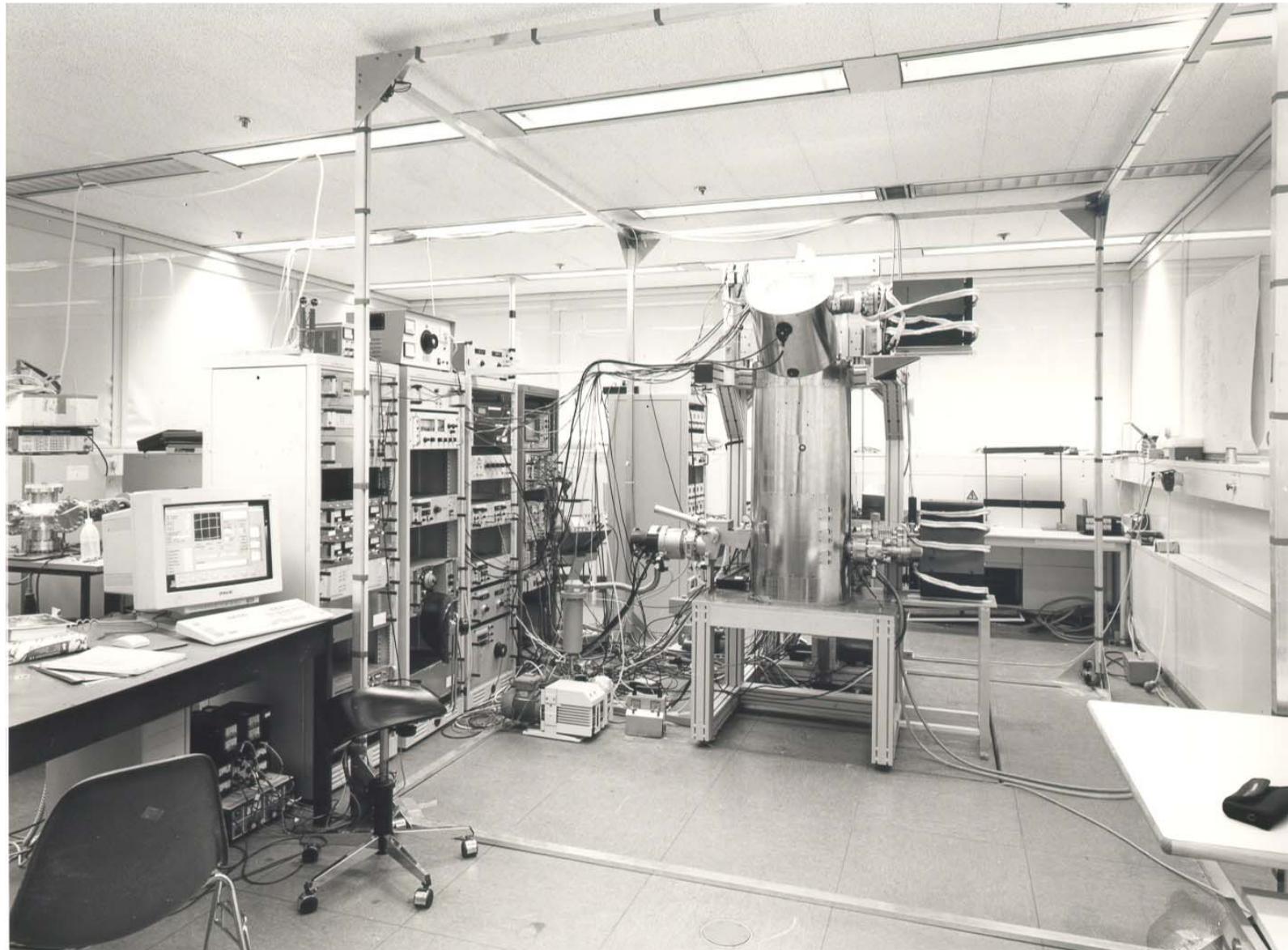


Scheme of the Munich Microscope

- moderated positrons are electrostatically focused, choppered and bunched
- second moderator stage allows focus down to about $2 \mu\text{m}$
- positron penetration energy adjustable for depth information
- instrument shall be adopted to the FRM-II positron source when available

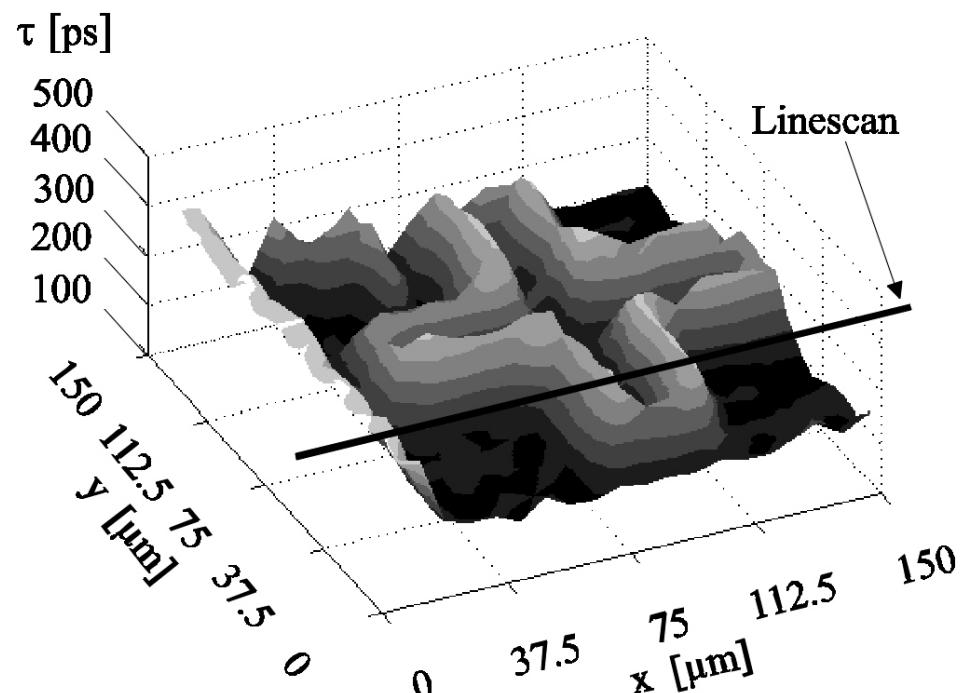


Scanning Positron Microscope in Munich

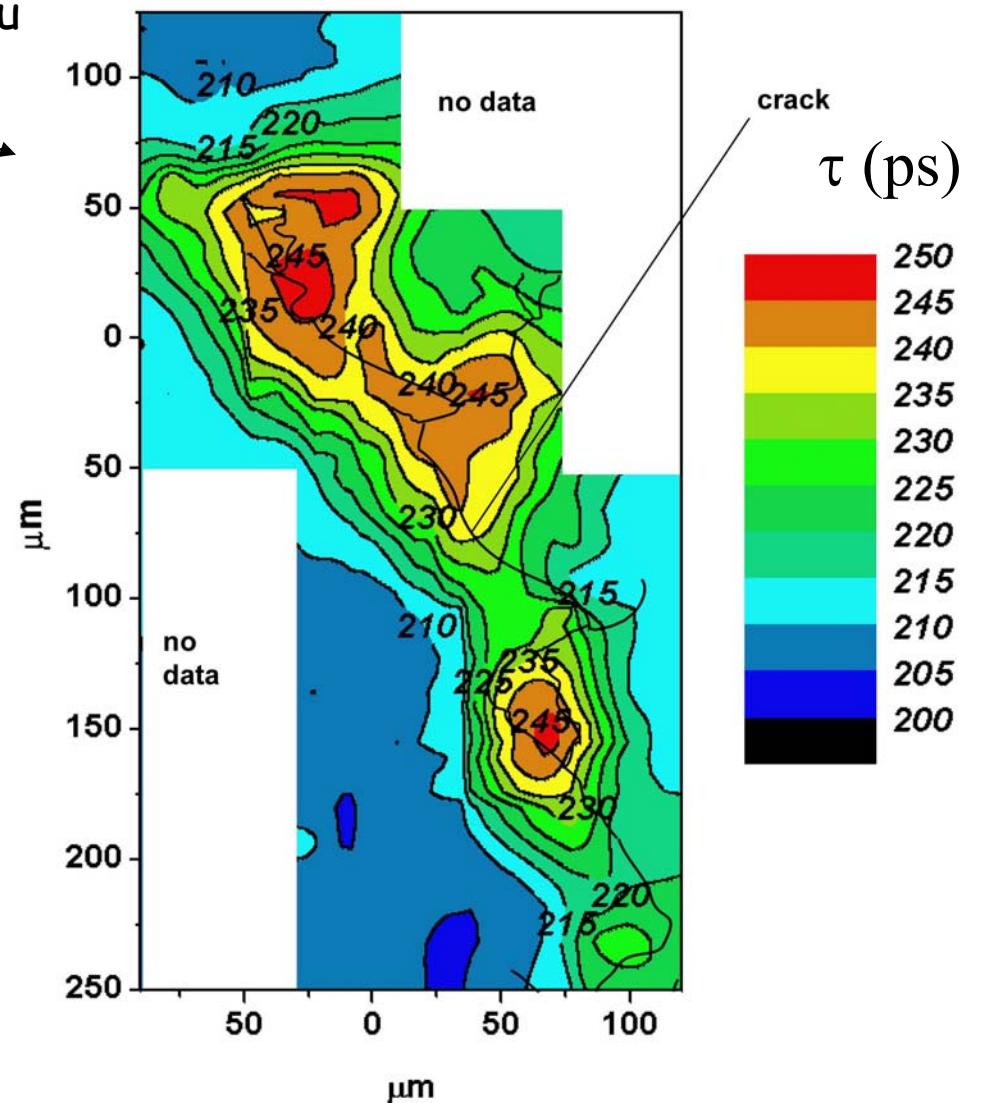


Scanning Positron Microscope in Munich

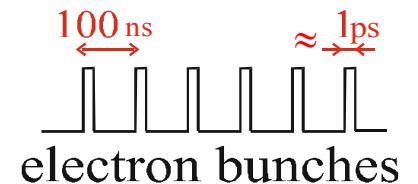
- defects near a crack in fatigued Cu
- Semiconductor test structure



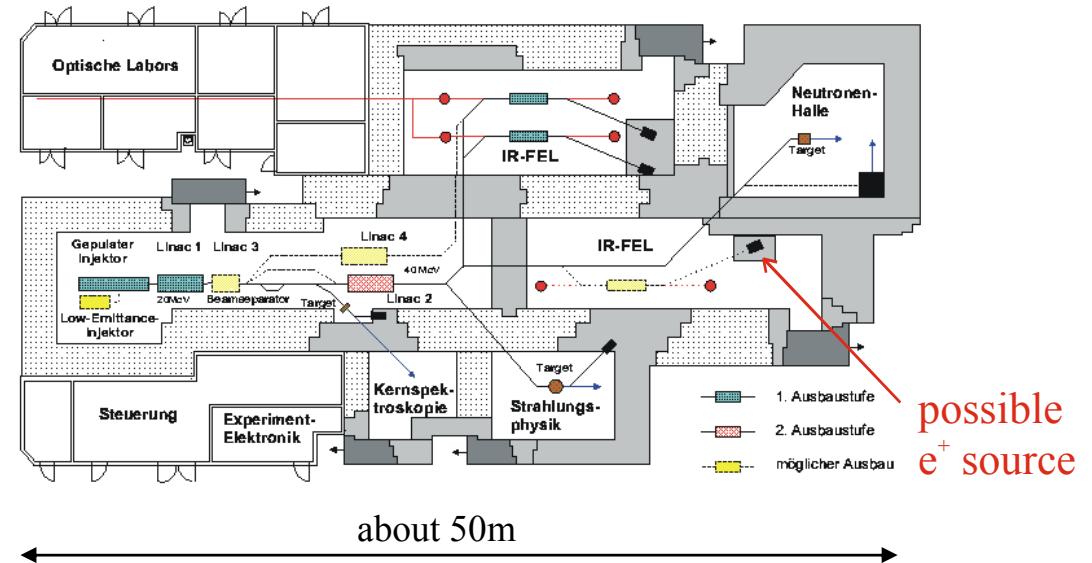
Nature 412 (2001) 764
Phys. Rev. Lett. 87 () 067402



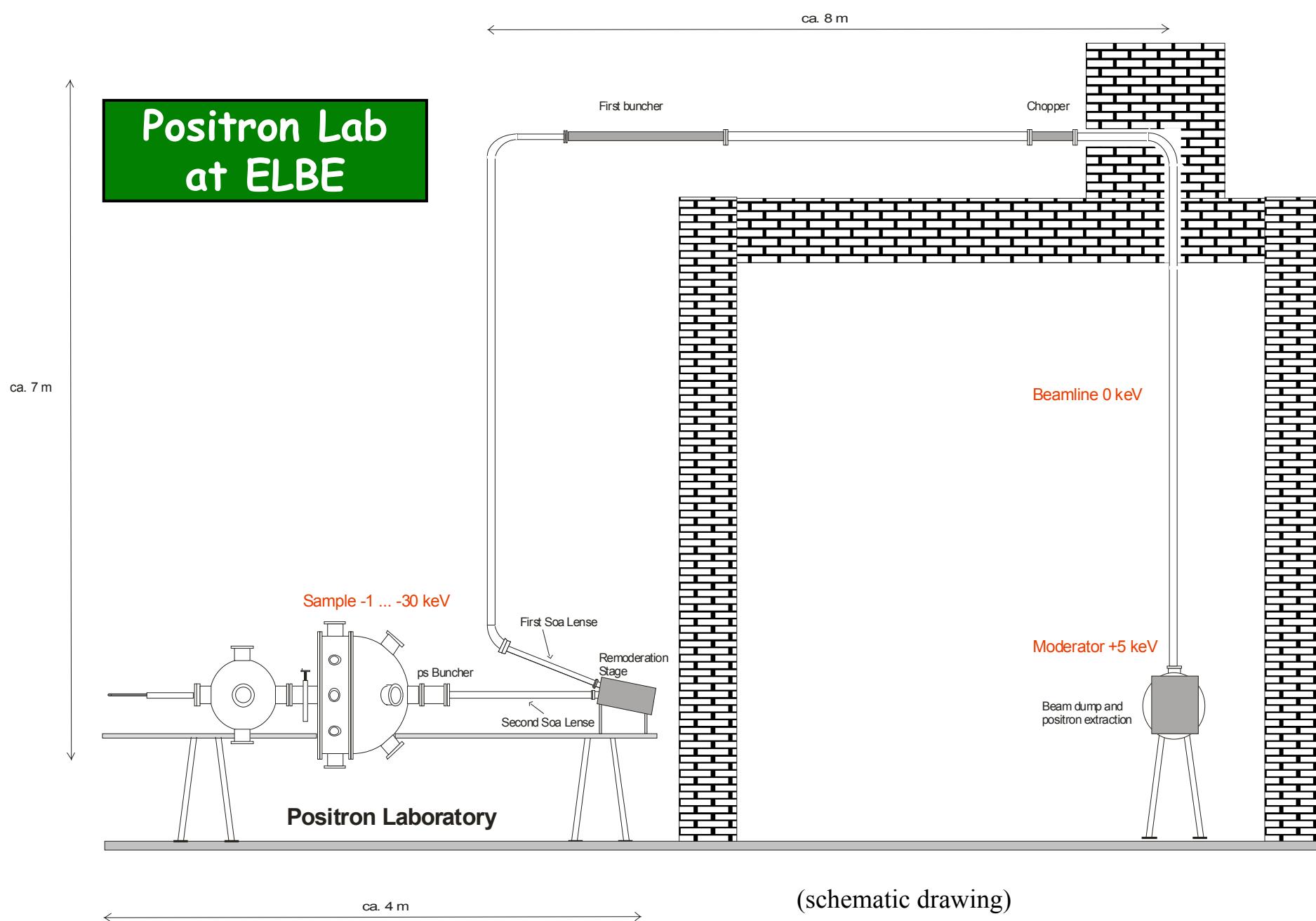
EPOS - Positron source at the Free-Electron Laser at ELBE



- electron beam at ELBE FEL is bunched
(length: ≈ 1 ps, repetition time: ≈ 100 ns,
cw-mode, up to 10^8 e-/bunch)
- beam energy: 40 MeV power: 40 kW
- FEL-system in Rossendorf under construction (ELBE)
- primary electron beam already available
- direct positron lifetime measurement using time structure of e⁻ beam possible
- about $2...5 \times 10^8$ slow e⁺/s; multidetector system for high counting rate
- combination with Doppler-coincidence spectroscopy (DOCOS) and Age-momentum correlation (AMOC)



Positron Lab at ELBE



Conclusions

- vacancy-type defects can be detected in solids by means of positron annihilation
- method very sensitive for early stage of vacancy agglomeration
- tools for thin layers (mono-energetic positron beams)
- scanning positron microbeams available
- intense positron sources under construction in Germany too

This presentation can be found as pdf-files on our Website:
<http://www.ep3.uni-halle.de/positrons>

contact: mail@PositronAnnihilation.net

